

COMPLEX ELECTRON MICROSCOPE

Patent Number: JP2002343294
Publication date: 2002-11-29
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Requested Patent: JP2002343294
Application Number: JP20020063728 20020308
Priority Number(s):
IPC Classification: H01J37/28; H01J37/26
EC Classification:
Equivalents:

Abstract

PROBLEM TO BE SOLVED: To provide a complex electron capable of obtaining accurate correspondence between the SEM/STEM image and TEM image.

SOLUTION: This complex electron microscope, capable of observing the SEM/STEM image and the TEM image, is provided with a first storage means 44 for storing SEM/STEM image rotation angle, magnification of the TEM image and the current value supplied to an imaging lens, in order to make the TEM image correspond to the SEM/STEM image rotation angle; a second storage means 45 for storing the magnification of the TEM image and the rotation angle, in order to make the SEM/STEM image correspond to the TEM image rotation angle; a computer 40 for correcting the magnification and the rotation angle according to the display mode, based on the data stored in the first and the second storage means; and a display means 35 for displaying the image corrected by the computer 40.

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